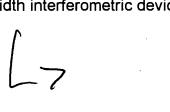
Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	4	(("5640270") or ("4848908")).PN.	USPAT; EPO; JPO; DERWENT	OR	OFF	2005/09/16 09:42
L2	10882	(measur\$3 or test\$3) near5 (roughness or smooth\$4 or crack\$4) near5 (surface or skin or texture or exterior)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 09:46
L3	75492	align\$5 near4 (beam or optical\$2)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 09:46
L4	105296	(reference or sample) near3 (surface or skin or texture or exterior)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 09:47
L5	76	2 and 3 and 4	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 09:47
L6	93628	(first or second or third) near3 beam	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 09:48
L7	37	5 and 6	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 12:37
L8	13	7 and (beam near9 (identical or exactly))	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:24
L9	252	(two or '2') near2 different\$2 near2 polariz\$5 near4 beam	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:26
L10	0	7 and 9	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:26
L11	5	7 and (different\$2 near2 polariz\$5 near4 beam)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:32
L12	9	7 and (measur\$3 near3 position)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:34
L13	0	7 and (alignment near9 rotation\$3)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:35
L14	0	5 and (alignment near9 rotation\$3)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:35
L15	10	7 and alignment and rotation\$3	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:36

L16	0	7 and alignment and (rotation\$3 near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:37
L17.	8	7 and (reflect\$3 near2 prism)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:39
L18	0	7 and (electronic near3 shutter) and multiplex\$3 and time	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:40
L19	0	7 and shutter and multiplex\$3 and time	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:40
L20	1	5 and shutter and multiplex\$3 and time	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:43
L21	18	7 and (cylindrical or tube or pipe)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:45
L22	14	21 and diameter	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 10:45
L23	4	22 and different near2 surface	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 12:38
L24	14	7 and different near2 surface	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 12:40
L25	14	7 and (different near2 surface)	USPAT; EPO; JPO; DERWENT	OR	ON	2005/09/16 12:40

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US 6490046 B1	Modulation interferom 356/489	356/477
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US 5640270 A	Orthogonal-scanning :359/368	250/201.3; 250/559.22; 356/511;
US 5469259 A	Inspection interferome 356/495	
US 4906094 A	Fine particle measurir 356/336	356/246; 356/339
US 4905311 A	Optical surface rough: 250/225	356/369
US 4848908 A	Optical heterodyne ro 356/489	
US 6930765 B2	Multiple spot size opti 356/73	
US 6909500 B2	Method of detecting a 356/237.3	257/E21.53
US 6897957 B2	Material independent 356/430	257/E21.53
US 6882437 B2	Method of detecting th 356/630	
US 6870126 B2	Semiconductor device 219/121.6	£219/121.73; 257/E21.347; 257/E2
US 6504618 B2	Method and apparatu: 356/630	356/632
US 6384916 B1	Parallel detecting, spe 356/369	
US 6226092 B1	Full-field geometricall: 356/512	
US 6172752 B1	Method and apparatu: 356/503	356/485; 356/517
US 6122065 A	Apparatus and metho 356/394	356/391; 356/623
US 6041020 A	Gas-coupled laser acc367/149	356/340; 356/341; 73/653
US 5889593 A	Optical system and mc356/445	
US 5737081 A	Extended-source low 356/511	
US 5715061 A	Optical measuring ap; 356/623	250/559.29
US 5651934 A	Recoating of stereolith 264/401	118/100; 118/120; 118/423; 118/4
US 5623509 A	Semiconductor laser ¿372/45.01	372/24; 372/46.01
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US 5523839 A	Differential optical inte 356/489	356/516
US 5141317 A	Method of optoelectro 356/488	356/499
US 5067817 A	Method and device for 356/613	
US 4995726 A	Surface profile measu 356/489	
US 4869593 A	Interferometric surface 356/495	
US 4732483 A	Interferometric surface 356/495	
US 4639139 A	Optical profiler using i 356/497	356/512
US 4576479 A	Apparatus and methor 356/495	
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US 3604804 A	NONCONTACTING M356/28	
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US 4906094 A Fine particle measurir 356/336 356/246; 356/339 US 4905311 A Optical surface rough₁250/225 356/369 US 6384916 B1 Parallel detecting, sp∈356/369 US 5523839 A Differential optical int∈356/489 356/516 US 4534649 A Surface profile interfe₁356/495

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US 5640270 A	Orthogonal-scanning 1359/368	250/201.3; 250/559.22; 356/511;
US 4905311 A	Optical surface rough: 250/225	356/369
US 6384916 B1	Parallel detecting, spe 356/369	
US 6226092 B1	Full-field geometricall 356/512	
US 5889593 A	Optical system and mr356/445	
US 5651934 A	Recoating of stereolith 264/401	118/100; 118/120; 118/423; 118/4
US 5623509 A	Semiconductor laser ¿372/45.01	372/24; 372/46.01
US 5608527 A	Apparatus and methor 356/600	356/445; 356/73
US 5067817 A	Method and device for 356/613	
US 4639139 A	Optical profiler using i 356/497	356/512
US 4576479 A	Apparatus and metho 356/495	
US 4534649 A	Surface profile interfer 356/495	
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